

Notice of References Cited

Application/Control No.

10/594,282

Applicant(s)/Patent Under
Reexamination
ISHII ET AL.

Examiner

Sin J. Lee

Art Unit

1795

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,093,517	07-2000	Ito et al.	430/270.1
*	B	US-5,683,856	11-1997	Aoi et al.	430/270.1
	C	US-			
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	E	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Sakamizu et al ("Structural Design of Resin Matrix and Acid-labile Dissolution Inhibitor of Chemical Amplification Positive Electron-beam Resist for Gigabit Lithography", Journal of Photopolymer Science and Technology, Vol.11, No.4 (1998), pg.547-552.
	V	
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.